



PATENT
Customer No. 22,852
Attorney Docket No. 04329.3178

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Yukiteru MATSUI et al.) Group Art Unit: 2812
)
Serial No.: 10/706,052) Examiner: Gurley, Lynne A.
)
Filed: November 13, 2003)
)
For: SLURRY FOR CMP, AND)
METHOD OF MANUFACTURING)
SEMICONDUCTOR DEVICE)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO RESTRICTION REQUIREMENT

In the Office Action dated March 25, 2004, the period for response to which extends through April 25, 2004, the Examiner required restriction under 35 U.S.C. § 121 between the following groups:

Group I, claims 8-20, characterized by the Examiner as drawn to a method of making a semiconductor device using a CMP slurry; and

Group II, claims 1-7, characterized by the Examiner as drawn to a CMP slurry.

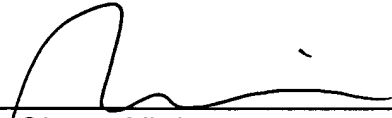
Applicants provisionally elect to prosecute Group I, including claims 8-20, without traverse.

Please grant any extensions of time required to enter this response and charge any additional required fees to our deposit account 06-0916.

Respectfully submitted,

FINNEGAN, HENDERSON, FARABOW,
GARRETT & DUNNER, L.L.P.

Dated: April 23, 2004

By: 
Qingyu Yin*

*With limited recognition under 37 C.F.R. § 10.9(b)